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FORM PTO-1449

INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(Use several sheets if necessary)

Docket Number (Optional)	Application Number
YOR920040020US1	10/804,553
Applicant: Colburn et al.	
Filing Date: March 19, 2004	Group Art Unit: 2812

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation YES	Translation NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

LP	Guarini et al., "*Optimization of Diblock Copolymer Thin Film Self-Assembly*", Advance Materials, vol. 4, NO. 18, September 16, 2002.
LP	Black et al., "*Integration of Self-Assembled Diblock Copolymers for Semiconductor Capacitor Fabrication*", Applied Physics Letters, vol. 79, No. 3, July 16, 2001.

EXAMINER	DATE CONSIDERED
Long Pham	5/27/05

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP §609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.